## プラズマ加熱用負イオンビーム位相空間構造に基づくビーム光学評価

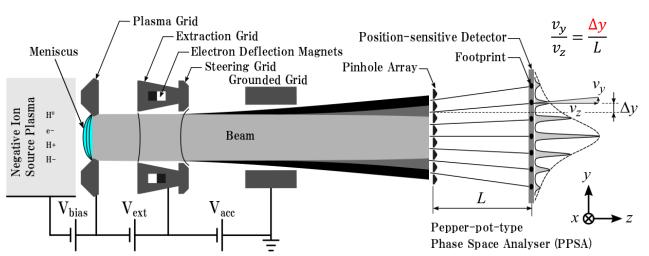
Evaluation of beam optical properties based on phase space structure of negative ion beams for plasma heating <u>Y.Haba</u><sup>1</sup>, K. Nagaoka<sup>2,1</sup>, K. Tsumori<sup>2,3</sup>, M. Kisaki<sup>2</sup>, H. Nakano<sup>2,3</sup>, K. Ikeda<sup>2</sup>, M. Osakabe<sup>2,3</sup>

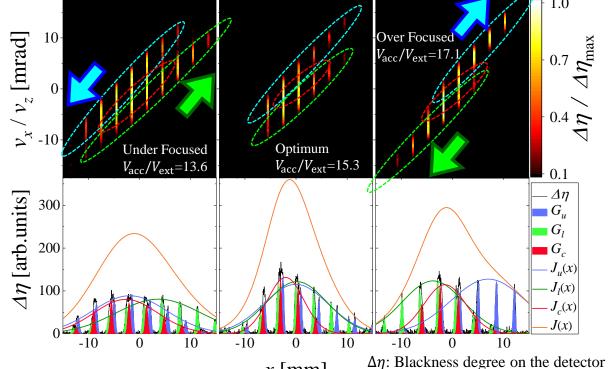
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Well-focused beam is required for ITER (3-7 mad with RF negative ion source).  $\rightarrow$  Achievement: 17-35 mrad with RF, ~5 mrad with filament-arc negative ion source

Beam focusing of negative ions are affected by two electrostatic-lens effects. One is the plasma meniscus, which is described as the perveance  $\propto n_{\rm H^-}/V_{\rm ext}^{1.5}$ , where  $n_{\rm H^-}$  and  $V_{\rm ext}$  refer the negative ion density and the extraction voltage, respectively. The other is the subsequent lens, which can be controlled by the voltage ratio of  $V_{\rm acc}/V_{\rm ext}$ , where  $V_{\rm acc}$  is the acceleration voltage.

We focus on the phase space structure of a single negative ion beamlet to understand the negative ion beam focusing. The phase space structure measurements of the beamlet produced by a filament-arc-type negative ion source (NIFS-RNIS) have been performed by scanning  $V_{\rm acc}/V_{\rm ext}$  with fixed perveance (fixed  $n_{\rm H^-}$  and  $V_{\rm ext}$ ).





x [mm] Diackness degree on the detector The beamlet consisting three-Gaussian components is identified in the *x*-direction. The two components, which are shown with dashed lines in blue and green, move in the opposite direction by changing  $V_{acc}/V_{ext}$ .

The standard deviation of the axis-positions of three components ( $\delta$ ) is a key parameter to characterize the focusing of the negative ion beamlet.

$$\delta = \left[\sum_{i} (x_i - \bar{x})^2 \alpha_i\right]^{1/2} / \sigma_x \quad \text{with} \quad \bar{x} = \sum_{i} x_i \alpha_i$$

 $x_i$ : Position of each component

- $\bar{x}$ : Position of beamlet center
- $\alpha_i$ : Normalized current

 $\sigma_x$ : Beamlet width